High-Current Tunneling FETs With (110) Orientation and a Channel Heterojunction

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Abstract-We propose InAs/GaSb ultrathin-body tunneling field-effect transistors (TFETs) using confinement in the (110) plane and transport in the [110] direction to increase the tunneling probability by reducing the tunnel barrier energy and hole effective mass. To reduce the OFF-state leakage current, we add an InAs/In_{1-n}Al_nAs_{1-n}Sb_n heterojunction to the channel, which increases the valence band barrier. The heterojunction also increases the tunneling probability and ON-current by reducing the tunneling distance through the p-n junction and introducing a resonant state. A fully atomistic non-equilibrium Green function quantum transport approach in NEMO5 is used to explore the design space. While choosing 10^{-3} A/m OFF-current (I_{OFF}) and a 0.3 V power supply, we simulate 270 A/m ON-current (ION) for a 30-nm gate length and 170 A/m for a 15-nm gate length (L_g) , while a conventional 15-nm L_g GaSb/InAs TFET under (001) confinement shows only 24 A/m I_{ON} .

Index Terms-Tunnel FETs, crystal orientation, band structure engineering, resonant tunneling.

I. INTRODUCTION

FUTURE VLSI performance is constrained by power dis-sipation [11] Low switching sipation [1]. Low switching power calls for a low supply voltage, yet decreased standby power calls for either increased voltages or reduced transistor subthreshold swing (S.S.). In conventional MOSFETs, the S.S. is limited to 60mV/dec by thermal injection [1]. Though tunnel FETs (TFETs) [2]-[4] can obtain smaller S.S., their ON current (I_{ON}) is limited by the PN junction tunneling probability [3], which is determined by the carrier effective mass and tunneling distance. In nanoscale TFETs confinement quantizes subbands and

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therefore increases the barrier energy and non-parabolic dispersions increase the carrier effective masses; both effects result in a decreased tunneling probability and reduced I_{ON} . The use of InAs/GaSb PN tunnel barriers reduces the tunneling barrier energy and tunneling distance, however at the desired layer thicknesses of a few nm, strong confinement and nonparabolic effects still reduce I_{ON} significantly. Alternative methods are needed to further increase I_{ON} .

Here we propose the concept to *increase* the confinement effective mass (to lower the confinement energy) and to decrease the transport effective mass (to increase the tunneling current). This can be achieved in the InAs material system by choosing the $(1\overline{1}0)$ plane for confinement and the [110] direction for transport. We also introduce an $InAs/In_{1-n}Al_nAs_{1-n}Sb_n$ heterojunction into the channel, and therefore resonantly enhance the tunneling probability in the ON-state and reduce the OFF-state source-drain tunneling leakage current.

II. CONFINEMENT AND TRANSPORT DIRECTIONS

III-V materials have strongly anisotropic heavy-hole bands [5], [6] hence 2-D hole subband structure is a strong function [5]-[7] of the confinement plane. (110) confinement provides subbands with low effective mass [8], particularly given [110] transport [9], [10]. For a $t_{ch} = 2$ nm thick channel, the hole effective mass reduces from 0.131m₀ given (001) confinement and [100] transport, or $0.19m_0$ given [110] transport, to $0.073m_0$ given $(1\overline{10})$ confinement and [110] transport. Further, because the heavy hole mass is larger in <110> than in <100>, the heavy hole subband energy shifts more slowly under $(1\overline{10})$ confinement than under (100). Compared to (100)confinement, at 2 nm t_{ch} , (110)-confined TFETs have lower hole effective mass and a smaller tunnel barrier energy (0.11eV vs. 0.15eV) between the GaSb source valence band and the InAs channel conduction band (Fig. 1a, b). The tunnel barrier is consequently thinner (Fig. 1c) and the tunneling probability higher (Fig. 1d).

The designs are based on a p-GaSb/n-InAs double-gate TFET (Fig. 2a). The gate oxide thickness is labeled t_{ox} and dielectric constant ε_r . The gate length is L_g , and source and drain doping densities are labeled N_S and N_D . The channel width extends in the z direction (perpendicular to the page). Table I lists the various design parameters. For (001)-confined

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Fig. 1. Conduction band structure of InAs and valence band structure of GaSb for a) ($1\overline{10}$) confined, and b) (001) confined UTBs. c) Band diagram under ON-state bias and d) transmission probability of ($1\overline{10}$) confined and (001) confined UTB GaSb/InAs TFETs. The channels are 2 nm thick, and $L_g = 15$ nm.



Fig. 2. Cross-section of a) a conventional GaSb/InAs TFET. b) Newly design heterostructure GaSb/InAs TFET with an InAs/ $In_{1-n}Al_nAs_{1-n}Sb_n$ heterojunction in the channel.

TFETs, the transport direction is [100], and the GaSb/InAs heterointerface is InSb-like. For $(1\bar{1}0)$ -confined TFETs, the transport direction is [110]. The channel is 2 nm thick; at 15 nm L_g , thicker channels suffer large source-drain tunneling leakage current. III-V MOSFETs with $T_{ch} = 2.5$ nm have been reported [11], [12].

Devices are simulated using the atomistic nanoelectronic modeling tool NEMO5 [13], which solves self-consistently the Poisson equation and the open boundary Schrödinger equation (quantum transmitting boundary method [14], [15]), using the 300K tight binding parameters of [16] and [17]; these give, in bulk, a 0.197 eV offset between the GaSb valence band and the InAs conduction band [18]. The InAlAsSb parameters are linearly interpolated using the virtual crystal approximation and are benchmarked against [19]. We integrate over the 1D Brillouin zone using a high order Gauss quadrature with 20 points. The simulations do not model carrier scattering. In [20]–[22], it is shown that phonon scattering slightly reduces TFET I_{on} , but does not significantly increase I_{off} . In the on-state, if carrier scattering is strong, the degree of resonant enhancement of the transmission will be decreased, and will degrade Ion. Trap-assisted tunneling and Shockley-Read-Hall thermal generation may also increase I_{off} and degrade S.S. [23]–[26] Increasing the alloy fraction n within the $In_{1-n}Al_nAs_{1-n}Sb_n$ channel will increase the channel bandgap and hence reduce thermal generation leakage currents.

Figure 1d demonstrates that in the energy range between the GaSb valence band and InAs conduction band, the TFET has a higher transmission probability with $(1\bar{1}0)$ compared to (001) confinement. At 30 nm L_g , I_{ON} increases from

TABLE I Parameters for GaSb/InAs Tunneling FETs

t_{ox}	2.56 nm	N_S	$5 \cdot 10^{19} \text{ cm}^{-3}$
t_{ch}	2 nm	N_D	$2 \cdot 10^{19} \text{ cm}^{-3}$
L_{g}	30 nm, 15 nm	$\mathcal{E}_{r,ox}$	9



Fig. 3. Off-state transmission probability a) and band diagram b) of (110)-confined GaSb/InAs TFETs with and without an InAs/In_{1-n}Al_n As_{1-n}Sb_n channel heterojunction. The transmission probability c) and band diagram d) are also shown in the ON state. x is the alloy fraction.

30A/m to 80A/m ($V_{\text{DD}} = 0.3$ V, $I_{\text{OFF}} = 10^{-3}$ A/m) comparing to a (001) confined TFET. However, undesired source-drain transmission at energies below the InAs conduction band edge is *increased* in the (110)-confined case (Fig. 1d) because InAs then has a smaller quantized bandgap (Fig. 1c) and smaller hole effective mass. The two-band S/D tunneling probability increases, and, at 15 nm L_g , the S.S. is degraded and, at fixed I_{OFF} , I_{ON} reduced.

III. CHANNEL HETEROJUNCTION

The introduction of an InAs/In_{1-x}Al_xAs_{1-x}Sb_x channel heterojunction (Fig. 2b) can improve both ON- and OFFstate performance, as reported in [27] and [28]. In the OFFstate, the heterojunction increases the valence-band barrier at the channel-source interface. This reduces the (two-band) S/D tunneling probability (Fig. 3a) in part because, under off-state bias (Fig. 3b), the energy separation between the InAs valence band and S/D tunneling evanescent states is increased, and in part because $In_{1-n}Al_nAs_{1-n}Sb_n$ has slightly larger electron effective mass $(0.067m_0)$ than InAs $(0.052m_0)$. The width of the InAs well is adjusted so that the single resonant state is aligned with InAlAsSb conduction band; in the InAs layer, there are no states at energies below the InAlAsSb conduction band. The lower edge of the transmission characteristics (Fig. 3a) becomes sharper, resulting in a steeper S.S., as will be seen subsequently. InAs is retained at the PN junction to maintain a small tunnel barrier energy for high I_{ON} .

Under ON-state bias (Fig. 3d), i.e. with the channel conduction band ~ 0.2 eV below the source valence band, inserting the



Fig. 4. Local density of states in the a) OFF state and b) ON state of a GaSb/InAs TFET with an InAs/In_{1-n}Al_nAs_{1-n}Sb_n (n = 0.14) channel heterojunction. The circled area indicates the resonant state.



Fig. 5. a) Transmission probability and b) band diagram of the GaSb/InAs tunneling junction for different InAs/In_{1-n}Al_nAs_{1-n}Sb_n heterojunctions. In all designs, the resonant state energy lies immediately above the In_{1-n}Al_nAs_{1-n}Sb_n conduction band. The TFETs have (110) confinement.

channel heterojunction increases the field in the PN tunnel barrier, reducing the PN junction tunneling distance hence increasing the tunneling probability (Fig. 3c). Inserting the channel heterojunction also introduces a resonant state in the InAs layer between the PN junction and the channel heterojunction (Fig. 4b). The tunneling probability is further increased by adjusting the $In_{1-n}Al_nAs_{1-n}Sb_n$ alloy fraction to align the resonant state energy to the channel conduction-band energy (Fig. 3c). This further improves I_{ON} .

To investigate the effect of the channel heterojunction on I_{ON} , independent of its effect on S/D tunneling, we first consider the case of 30 nm L_g . We simulate (Fig. 5b) a series of designs with varying InAs channel length d, while varying the In_{1-n}Al_nAs_{1-n}Sb_n alloy fraction x such that the lowest resonant state in the InAs layer always lies immediately above the In_{1-n}Al_nAs_{1-n}Sb_n conduction band.

As the InAs layer is progressively thinned and the alloy fraction *n* simultaneously increased, the InAs/In_{1-n}Al_nAs_{1-n}Sb_n conduction band offset increases, and the energy separation between the InAs resonant state (aligned with the In_{1-n}Al_nAs_{1-n}Sb_n conduction band) and the InAs conduction band increases (Fig. 5(b)). The PN junction tunneling distance therefore progressively decreases (Fig. 5b), progressively increasing I_{ON} (Fig. 6a). With $V_{DD} = 0.3V$ and



Fig. 6. Transfer characteristics of a) 30 nm L_g and b) 15 nm L_g (110)-confined TFETs for different In_{1-n}Al_nAs_{1-n}Sb_n heterojunction band profiles. Results are compared to (110)- and (001)-confined TFETs with no channel heterojunction.

 $I_{\text{OFF}} = 10^{-3}$ A/m, and with (110) confinement, I_{ON} increases from 80A/m (n=0) to 270A/m (n = 0.14, d = 4.5 nm).

At 15 nm L_g , S/D tunneling is larger, and the InAs/In_{1-n}Al_nAs_{1-n}Sb_n heterojunction provides a greater improvement in the ON/OFF current ratio. With $V_{DD} = 0.3V$ and $I_{OFF} = 10^{-3}$ A/m, and with (110) confinement, as the AlSb mole fraction *n* increases, I_{ON} increases from 5A/m (*n* = 0) to 170A/m (*n* = 0.14, *d* = 4.5 nm). The (001)-confined TFET shows 24A/m I_{ON} .

A similar P-channel TFET design would use an N-InAs source, a channel containing a GaSb/AlGaSb heterojunction, a P+ AlGaSb drain, $(1\overline{10})$ confinement, and [110] transport.

IV. SUMMARY

It is found that using the (110) confinement plane and the [110] transport direction improves I_{ON} compared to (001)- confined TFETs. Introducing an InAs/ In_{1-n}Al_nAs_{1-n}Sb_n channel heterojunction reduces the S/D tunneling and improves the *S.S.* Further, the channel heterojunction greatly increases I_{ON} , both by decreasing the tunneling distance and by introducing a resonant state. Within this design space a 15 nm gate length TFET with 170A/m ON current can be obtained.

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